



TRANSMITTAL FORM

(to be used for all correspondence after initial filing)

Approved for use through 08/30/2003. OMB 0651-0031
U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE
Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it displays a valid OMB control number.

		Application Number	10/687,519
		Filing Date	October 16, 2003
		First Named Inventor	Van Nguyen Truskett
		Art Unit	1762
		Examiner Name	Unassigned
Total Number of Pages in This Submission		Attorney Docket Number	P75/MII-35-17-03

ENCLOSURES (Check all that apply)		
<input type="checkbox"/> Fee Transmittal Form <input type="checkbox"/> Fee Attached <input type="checkbox"/> Amendment/Reply <input type="checkbox"/> After Final <input type="checkbox"/> Affidavits/declaration(s) <input type="checkbox"/> Extension of Time Request <input type="checkbox"/> Express Abandonment Request <input checked="" type="checkbox"/> Information Disclosure Statement <input type="checkbox"/> Certified Copy of Priority Document(s) <input type="checkbox"/> Response to Missing Parts/ Incomplete Application <input type="checkbox"/> Response to Missing Parts under 37 CFR 1.52 or 1.53	<input type="checkbox"/> Drawing(s) <input type="checkbox"/> Licensing-related Papers <input type="checkbox"/> Petition <input type="checkbox"/> Petition to Convert to a Provisional Application <input type="checkbox"/> Power of Attorney, Revocation <input type="checkbox"/> Change of Correspondence Address <input type="checkbox"/> Terminal Disclaimer <input type="checkbox"/> Request for Refund <input type="checkbox"/> CD, Number of CD(s)	<input type="checkbox"/> After Allowance communication to Technology Center (TC) <input type="checkbox"/> Appeal Communication to Board of Appeals and Interferences <input type="checkbox"/> Appeal Communication to TC (Appeal Notice, Brief, Reply Brief) <input type="checkbox"/> Proprietary Information <input type="checkbox"/> Status Letter <input checked="" type="checkbox"/> Other Enclosure(s) (please identify below): <input type="checkbox"/> Form 1449 - IDS <input type="checkbox"/> Fifty-eight (58) References <input type="checkbox"/> Return Receipt Postcard to Kenneth Brooks
Remarks		

SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT

Firm or Individual name	Law Office of Kenneth C. Brooks
Signature	
Date	February 26, 2004

CERTIFICATE OF TRANSMISSION/MAILING

I hereby certify that this correspondence is being facsimile transmitted to the USPTO or deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on the date shown below.

Typed or printed name	Alexis Sheffield
Signature	
	Date February 26, 2004

This collection of information is required by 37 CFR 1.5. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to 12 minutes to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: **Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450**.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Truskett et al.

PATENT APPLICATION

Serial No.: 10/687,519

Group Art Unit: 1762

Filing Date: October 16, 2003

Examiner: Unassigned

For: LOW SURFACE ENERGY TEMPLATES

INFORMATION DISCLOSURE STATEMENT

Commissioner
for Patents
Alexandria, VA 22313-1450

Sir:

The following information is submitted in compliance with Applicants' duty of disclosure under 37 C.F.R. § 1.56. Form PTO-1449 and a copy of each reference recited below accompanies this document. It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

ISSUED PATENTS

<u>Patent Number</u>	<u>Inventor</u>	<u>Grant Date</u>
4,544,572	Sandvig	10/01/1985
4,731,155	Napoli et al.	03/15/1988
4,959,252	Bonnebat et al.	09/25/1990
5,206,983	Guckel et al.	05/04/1993
5,259,926	Kuwabara et al.	11/09/1993
5,425,848	Haisma et al.	06/20/1995
5,480,047	Tanigawa et al.	01/02/1996
5,512,131	Kumar et al.	04/30/1996
5,725,788	Maracas et al.	03/10/1998
5,772,905	Chou	06/30/1998
5,776,748	Singhvi et al.	07/07/1998
5,900,160	Whitesides et al.	05/04/1999
5,948,470	Harrison et al.	09/07/1999
6,039,897	Lochhead et al.	03/21/2000
6,117,708	Wensel	09/12/2000

6,128,085	Buermann et al.	10/03/2000
6,143,412	Schueller et al.	11/07/2000
6,168,845	Fontana, Jr. et al.	01/02/2001
6,180,239	Whitesides et al.	01/30/2001
6,218,316	Marsh	04/17/2001
6,309,580	Chou	10/20/2001
6,334,960	Willson et al.	01/01/2002
6,355,198	Kim et al.	03/12/2002
6,518,168	Clem et al.	02/11/2003

OTHER PATENT DOCUMENTS

09/698,317	Choi et al.	10/27/2000
09/907,512	Sreenivasan et al.	07/16/2001
09/908,455	Choi et al.	07/17/2001
09/920,341	Choi et al.	08/01/2001
09/934,248	Choi et al.	08/21/2001
09/976,681	Bailey et al.	10/12/2001
10/136,188	Voisin	05/01/2002
09/905,718	Willson et al.	05/16/2002
10/178,947	Watts et al.	06/24/2002
10/375,817	Nguyen et al.	02/27/2003
10/375,832	Nguyen et al.	02/27/2003
10/463,396	Choi et al.	06/17/2003

FOREIGN PATENT DOCUMENTS

<u>Document No.</u>	<u>Inventor</u>	<u>Pub. Date</u>
DE 2800476	Lamprecht et al.	07-13-1978
JP 1-196749	Matsumoto et al.	08-08-1989
WO 01/53889	Ling et al.	07-26-2001
WO 01/90816	Heidari	11-29-2001

NON-PATENT DOCUMENTS

Gokan et al. "Dry Etch Resistance of Organic Materials," *J. Electrochem. Soc.*, 130:1, pp. 143-146, Jan. 1983.

Lin. "Multi-Layer Resist Systems: Introduction of Microlithography," *American Chemical Society*, pp. 287-350, 1983.

Cowie, J.M.G. "Polymers: Chemistry and Physics of Modern Materials," 2nd Ed., pp. 408-409, 1991.

Krug, Herbert et al. "Fine Patterning of Thin Sol-Gel Films," *Journal of Non-Crystalline Solids*, pp. 447-450, 1992.

Kotachi et al. "Si-Containing Positive Resist for ArF Excimer Laser Lithography," *J. Photopolymer Sci. Technol.*, 8(4) pp. 615-622, 1995.

Krauss, et al. "Fabrication of Nanodevices Using Sub-25nm Imprint Lithography," *Appl. Phys. Lett.*, 67(21), pp. 3114-3116, 1995.

Chou et al. "Imprint of Sub-25 nm Vias and Trenches in Polymers," *Applied Physics Letters*, 67(21), pp. 3114-3116, 1995.

Chou et al. "Imprint Lithography with 25-Nanometer Resolution," *Science*, vol. 272, pp. 85-87, Apr. 5, 1996.

Haisma, J. et al. "Mold-Assisted Nanolithography: A Process for Reliable Pattern Replication," *Journal of Vacuum Science and Technology*, vol. 14, pp. 4124-4128, 1996.

Chou et al. "Imprint Lithography with Sub-10 nm Feature Size and High Throughput", *Microelectronic Engineering* 35, pp. 237-240, 1997.

Scheer, H.C. et al. "Problems of Nanoimprinting Technique for Nanometer Scale Pattern Definition," *Journal of Vacuum Science and Technology*, vol. 16, pp. 3917-3921, 1998.

Xia, Y. et al. "Soft Lithography," *Annu. Rev. Mater. Sci.*, vol. 28, pp. 153-184, 1998.

Xia et al. "Soft Lithography," *Agnew. Chem. Int. Ed.*, vol. 37, pp. 550-575, 1998.

Colburn, M. et al. "Step and Flash Imprint Lithography: New Approach to High-Resolution Patterning," *Proc. of SPIE*, vol. 3676, pp. 379-389, 1999.

Chou, Stephen et al. "Lithographically-induced Self Assembly of Periodic Micropillar Arrays," *Journal of Vacuum Science and Technology*, vol. 17, pp. 3197-3202, 1999.

Choi, B.J. et al. "Design of Orientation Stages for Step and Flash Imprint Lithography," *Precision Engineering*, vol. 25, pp. 192-199, 2001.

Chou. "Nanoimprint Lithography and Lithographically Induced Self-Assembly," *MRS Bulletin*, pp. 512-517, July 2001.

Nguyen, A. Q. "Asymmetric Fluid-Structure Dynamics in Nanoscale Imprint Lithography," University of Texas at Austin, August 2001.

CERTIFICATE OF MAILING

Respectfully Submitted,

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in a package addressed to: MAIL STOP PATENT APPLICATION, Commissioner for Patents, Alexandria, VA 22313-1450

Signed: Alexis Sheffield
 Typed Name: Alexis Sheffield
 Date: Feb. 26, 2004

Respectfully,

Kenneth C. Brooks
 Reg. No. 38,393

P.O. Box 81536
 Austin, Texas 78708-1536
 Telephone: 512-527-0104
 Facsimile: 512-527-0107
patentsrus@earthlink.net



Please type a plus sign (+) inside this box

→

PTO/SB/08A (08-00)

Approved for use through 10/31/2003 OMB 0651-0031

Approved for use through 10/31/2002. OMB 0851-0031
U.S. Patent and Trademark Office: U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it displays a valid OMB control number.

Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet

1

0

5

Attorney Docket Number

P75/MII-35-17-03

Application Number	10/687,519
Filing Date	10/16/2003
First Named Inventor	Truskett et al.
Group Art Unit	1762
Examiner Name	Unassigned
Attorney Docket Number	P75/MII-35-17-03

U.S. PATENT DOCUMENTS

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Unique citation designation number. ²See attached Kinds of U.S. Patent Documents. ³Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶Applicant is to place a check mark here if English language Translation is attached.

Burden Hour Statement: This form is estimated to take 2.0 hours to complete. Time will vary depending upon the needs of the individual case. Any comments on the amount of time you are required to complete this form should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, Washington, DC 20231. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Assistant Commissioner for Patents, Washington, DC 20231.